

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re PATENT APPLICATION of :

Woon-kyung LEE et al. : Attn: Applications Branch  
Serial No.: [NEW] : Attorney Docket No.: SEC.697D  
Filed: 17 November 2003 :  
For: MASK ROM FABRICATION METHOD

**CLAIM OF PRIORITY**

U.S. Patent and Trademark Office  
2011 South Clark Place  
Customer Window  
Crystal Plaza Two, Lobby, Room 1B03  
Arlington, VA 22202

Sir:

Applicant, in the above-identified application, hereby claims the priority date  
under the International Convention of the following Korean application:

Appln. No. 1999-16605                      filed May 10, 2000

as acknowledged in the Declaration of the subject application.

A certified copy of said application was submitted in the parent application.

Respectfully submitted,

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Dated: 17 November 2003

대한민국 특허청  
KOREAN INDUSTRIAL  
PROPERTY OFFICE

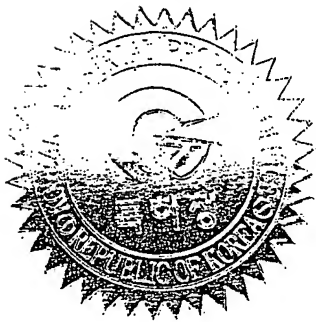
별첨 사본은 아래 출원의 원본과 동일함을 증명함.

This is to certify that the following application annexed hereto  
is a true copy from the records of the Korean Industrial  
Property Office.

출원 번호 : 1999년 특허출원 제16605호  
Application Number

출원 년 월 일 : 1999년 5월 10일  
Date of Application

출원인 : 삼성전자 주식회사  
Applicant(s)



1999 년 5 월 28 일

특 허 청

COMMISSIONER

